# 502014352 08/06/2012

#### PATENT ASSIGNMENT

Electronic Version v1.1 Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	EXECUTIVE ORDER 9424, CONFIRMATORY LICENSE

#### **CONVEYING PARTY DATA**

Name	Execution Date
Massachusetts Institute of Technology	07/17/2012

### **RECEIVING PARTY DATA**

Name:	National Science Foundation	
Street Address:	4201 Wilson Blvd	
Internal Address:	Room 1265	
City:	Arlington	
State/Country:	VIRGINIA	
Postal Code:	22230	

## PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	13081762

## **CORRESPONDENCE DATA**

Fax Number: 7032929242
Email: nsfpatents@nsf.gov

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent

via US Mail.

Correspondent Name: National Science Foundation

Address Line 1: 4201 Wilson Blvd Address Line 2: Room 1265

Address Line 4: Arlington, VIRGINIA 22230

NAME OF SUBMITTER: Dana Thibodeau

Total Attachments: 1 source=63#page1.tif

PATENT 502014352 REEL: 028726 FRAME: 0965

# **License to the United States Government**

Sign and submit the executed document to the appropriate funding agency (e.g. upload in lEdison).
nvention Title: A Fabrication Method to Obtain Large Area Hexagonal Boron Nitride Thin Film on
Arbitrary Substrates
nventor(s): Jing Kong, Yumeng Shi, Christoph Hamsen, Lain-Jong Li
U.S. Filing/Issue Date: 04/07/2011
Patent or Application Serial No.: 13/081, 762
Grant/Contract Number(s): DMR0845358
Foreign Applications filed/intended in (countries):
The invention identified above is a Subject Invention under <b>35 U.S.C. 200, et seq.</b> , and the Standard Patent Rights clause at <b>37 CFR 401.14, FAR 52.227-11</b> or <b>FAR 52.227-12</b> (if applicable) which are included among the terms of the above identified grant or contract award from the United State Government. This document is confirmatory of:
<ol> <li>The nonexclusive, nontransferable, irrevocable, paid-up license to practice or have practiced for or on behalf of the United States the invention described in any patent application and in any and all divisions, continuations, and continuations in part, and in any and all patents and re-issues granted thereon throughout the world; and</li> <li>All other rights acquired by the Government by reason of the above identified grant/contract award and the laws and regulations that are applicable to the award.</li> </ol>
The Government is hereby granted an irrevocable power to inspect and make copies of the above-identified pater application.
Signed this 17th day of July , 20 12
By Rolande Johndro (Institutional Business Official) (Signature)
Title Patent Compliance Administrator
For MASSACHUSETTS INSTITUTE OF TECHNOLOGY (Grantee/Contractor Organization)
At MIT Technology Licensing Office NE18-501 One Cambridge Center, Kendall Square
Cambridge, MA 02142 US (Business Address)

PATENT REEL: 028726 FRAME: 0966

**RECORDED: 08/06/2012**